Special Issue

Application of Deep Learning in Medical Imaging

Message from the Guest Editors

This Special Issue will focus on innovative research in the applications of deep learning in medical imaging, covering architecture designs, task applications, clinical research, and model deployment. It will emphasize large-scale dataset establishment, model structure development, trustworthy and robust deployment in real-world care pathways, and the translation of models across diverse clinical tasks, driving cutting-edge exploration and practice in medical AI technology.

Topics of interest include but, are not limited to, the following:

- Development, validation, and application of deep learning-based model in medical imaging;
- Establish of large-scale standardized clinical datasets;
- Applications in different medical modalities;
- Explainability and uncertainty research for clinical decision support;
- Self-supervised and weakly supervised learning for annotation reduction;
- Federated, privacy-preserving, and domain adaptation frameworks addressing data fragmentation.

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